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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Hiroyuki OHTA**

Group Art Unit: **2812**

Serial No.: **10/668,211**

Examiner: **Walter L. Lindsay, Jr.**

Filed: **September 24, 2003**

Confirmation No.: **1590**

For: **REDUCTION IN SOURCE-DRAIN RESISTANCE OF SEMICONDUCTOR DEVICE**

Attorney Docket Number: **031106**  
Customer Number: **38834**

**RESPONSE TO RESTRICTION REQUIREMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

October 7, 2004

Sir:

This paper is submitted in response to the Official Action dated September 7, 2004.

In the Action, restriction is required between Group I (Claims 16-19) and Group II, Claims (1-15).

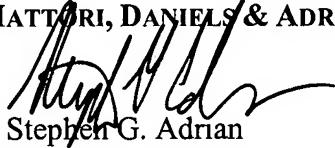
Applicant hereby elects the subject matter of Group II (Claims 1-15) for prosecution in this application. This election is made without traverse, and it is understood that Applicants' rights to the filing of a divisional application directed to the non-elected subject matter under 35 U.S.C. §120 and 35 U.S.C. §121 are retained.

Response to Restriction Requirement  
Serial No. 10/668,211  
Attorney Docket No. 031106

If this paper is not timely filed, Applicant respectfully petitions for an appropriate extension of time. The fees for such an extension or any other fees that may be due with respect to this paper may be charged to Deposit Account No. 50-2866.

Respectfully submitted,

**WESTERMAN, HATTORI, DANIELS & ADRIAN, LLP**



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